

Title (en)
AN ILLUMINATION SOURCE AND ASSOCIATED METROLOGY APPARATUS

Title (de)
BELEUCHTUNGSQUELLE UND ZUGEHÖRIGE MESSVORRICHTUNG

Title (fr)
SOURCE D'ÉCLAIRAGE ET APPAREIL DE MÉTROLOGIE ASSOCIÉ

Publication
EP 3962241 A1 20220302 (EN)

Application
EP 20192841 A 20200826

Priority
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Abstract (en)
Disclosed is an illumination source comprising a gas delivery system being configured to provide a gas target for generating an emitted radiation at an interaction region of the gas target, and an interferometer for illuminating at least part of the gas target with an interferometer radiation to measure a property of the gas target.

IPC 8 full level
H05G 2/00 (2006.01)

CPC (source: EP)
H05G 2/003 (2013.01); **H05G 2/008** (2013.01)

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Designated extension state (EPC)
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